

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Kanakasabapathi Subramanian et al.

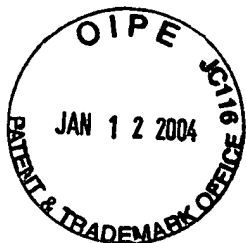
Title: THREE DIMENSIONAL HIGH ASPECT RATIO MICROMACHINING

Docket No.: 1153.071US1

Filed: June 27, 2003

Examiner: Unknown

Customer No.: 21186



Serial No.: 10/607,838

Due Date: N/A

Group Art Unit: 2811

Confirmation No.: 8463

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

We are transmitting herewith the following attached items (as indicated with an "X"):

☒ A return postcard.

☒ An Information Disclosure Statement (2 pgs.), Form 1449 (1 pg.), and copies of 15 cited documents.

If not provided for in a separate paper filed herewith, Please consider this a PETITION FOR EXTENSION OF TIME for sufficient number of months to enter these papers and please charge any additional fees or credit overpayment to Deposit Account No. 19-0743.

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.

Customer Number 21186

By: Bradley A. Forrest
Atty: Bradley A. Forrest
Reg. No. 30,837

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail, in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on this 9th day of January, 2004.

Gulim Abilova
Name

Gulim Abilova
Signature

SCHWEGMAN, LUNDBERG, WOESSNER & KLUTH, P.A.
(GENERAL)

Customer Number 21186



S/N 10/607,838

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

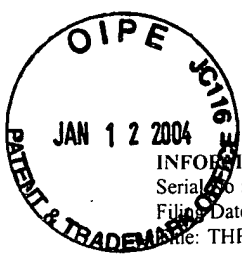
Applicant:	Kanakasabapathi Subramanian et al.	Examiner:	Unknown
Serial No.:	10/607,838	Group Art Unit:	2811
Filed:	June 27, 2003	Docket:	1153.071US1
Title:	THREE DIMENSIONAL HIGH ASPECT RATIO MICROMACHINING		

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

In compliance with the duty imposed by 37 C.F.R. § 1.56, and in accordance with 37 C.F.R. §§ 1.97 *et. seq.*, the enclosed materials are brought to the attention of the Examiner for consideration in connection with the above-identified patent application. Applicants respectfully request that this Information Disclosure Statement be entered and the documents listed on the attached Form 1449 be considered by the Examiner and made of record. Pursuant to the provisions of MPEP 609, Applicants request that a copy of the 1449 form, initialed as being considered by the Examiner, be returned to the Applicants with the next official communication.

Pursuant to 37 C.F.R. §1.97(b), it is believed that no fee or statement is required with the Information Disclosure Statement. However, if an Office Action on the merits has been mailed, the Commissioner is hereby authorized to charge the required fees to Deposit Account No. 19-0743 in order to have this Information Disclosure Statement considered.



INFORMATION DISCLOSURE STATEMENT

Serial No.: 10/607838

Filing Date: June 27, 2003

Title: THREE DIMENSIONAL HIGH ASPECT RATIO MICROMACHINING

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Dkt: 1153.071US1

The Examiner is invited to contact the Applicants' Representative at the below-listed telephone number if there are any questions regarding this communication.


Respectfully submitted,

KANAKASABAPATHI SUBRAMANIAN ET AL.

By their Representatives,

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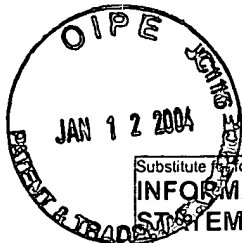
Date 1-9-2004

By 
Bradley A. Forrest
Reg. No. 30,837

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Gulim Abilova
Name


Signature



Substitute for Form 1449A/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Complete if Known

Application Number	10/607,838
Filing Date	June 27, 2003
First Named Inventor	Subramanian, Kanakasabapathi
Group Art Unit	2811
Examiner Name	Unknown

Sheet 1 of 1

Attorney Docket No: 1153.071US1

US PATENT DOCUMENTS

Examiner Initial *	USP Document Number	Publication Date	Name of Patentee or Applicant of cited Document	Class	Subclass	Filing Date If Appropriate
	US-5,198,390	03/30/1993	MacDoanld, Noel C., et al.	437	203	01/16/1992
	US-5,536,988	07/16/1996	Zhang, Z. Lisa, et al.	310	309	06/01/1993
	US-5,628,917	05/13/1997	MacDonald, Noel C., et al.	216	2	02/03/1995
	US-5,770,465	06/23/1998	MacDonald, Noel C., et al.	437	67	06/21/1996
	US-6,000,280	12/14/1999	Miller, Scott A., et al.	73	105	03/23/1998
	US-6,073,484	06/13/2000	Miller, Scott A., et al.	73	105	07/19/1996

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Foreign Document No	Publication Date	Name of Patentee or Applicant of cited Document	Class	Subclass	T ²
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OTHER DOCUMENTS -- NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		ALBRECHT, T. R., et al., "Microfabrication of integrated scanning tunneling microscope", <u>Journal of Vacuum Science & Technology A (Vacuum, Surfaces, and Films)</u> , 8(1), (January-February 1990), 317-318	
		HOFMANN, W., et al., "Monolithic three-dimensional single-crystal silicon microelectromechanical systems", <u>Sensors and Materials</u> , 10(6), (1998), 337-350	
		MILLER, S. A., "Microelectromechanical scanning probe instruments for array architectures", <u>Review of Scientific Instruments</u> , 68(11), (November 1997), 4155-62	
		SHAW, K. A., et al., "SCREAM I: a single mask, single-crystal silicon, reactive ion etching process for microelectromechanical structures", <u>Sensors and Actuators A (Physical)</u> , A40 (1), (1994), 63-70	
		TIROLE, N., et al., "3D silicon electrostatic microactuator", <u>Journal of Micromechanics and Microengineering</u> , 3(3), (September 1993), 155-157	
		TIROLE, N., et al., "Three-dimensional silicon electrostatic linear microactuator", <u>Sensors and Actuators A (Physical)</u> , A48 (2), (May 1995), 145-150	
		WEBB, R. Y., et al., "Suspended thermal oxide trench isolation for SCS MEMS", <u>Proceedings of the SPIE - The International Society for Optical Engineering</u> , 3519, (1998), 196-199	
		XU, Y., et al., "Integrated micro-scanning tunneling microscope", <u>Applied Physics Letters</u> , 67(16), (October 1995), 2305-2307	
		ZHANG, Z. L., et al., "A RIE process for submicron, silicon electromechanical structures", <u>Journal of Micromechanics and Microengineering</u> , 2 (1), (March 1992), 31-38	

EXAMINER

DATE CONSIDERED

Substitute Disclosure Statement Form (PTO-1449)

* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. Applicant's unique citation designation number (optional) 2 Applicant is to place a check mark here if English language Translation is attached